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SHEET 1 OF 1

Substitute for form 1449A/P

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

ATTORNEY'S DKT NO.
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APPLICATION No.
09/895,403

APPLICANT
Nobuo YAMGUCHI





FILING DATE
July 3, 2001

**GROUP
2812**



U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

Examiner Initials	Foreign Patent Document		Country	Date of Publication (MM-DD-YYYY)	Translation	
	Number	Kind Code (if known)			Yes	no
	11-195260		JAPAN	07-02-1999	abstract	
	10-163308		JAPAN	06-19-1998	abstract	
	09-087839		JAPAN	03-31-1997	abstract	
	63-310965		JAPAN	12-19-1988	abstract	

NON-PATENT LITERATURE DOCUMENTS

Examiner Initials	Include name of author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.		
	Electrostatic Clamping Applied to Semiconductor Plasma Processing, <i>J. Electrochem. Soc.</i> , Vol. 140, No. 11, November 1993, The Electrochemical Society, Inc., pp. 3245-3255		
Examiner Signature		Date Considered	1-21-05

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. SEND TO: Assistant Commissioner for Patents, Washington, D.C. 20231.

{05/01}